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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re application of : **Mail Stop: ISSUE FEE**  
Shoriki NARITA et al. : **Confirmation No. 1853**  
Serial No. 10/019,700 ✓ : [Group Art Unit 2825]  
Filed January 2, 2002 : Examiner Igwe U. Anya]

BUMP FORMING APPARATUS FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVAL METHOD  
FOR CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVING UNIT FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, AND CHARGE APPEARANCE  
SEMICONDUCTOR SUBSTRATE

### RESUBMISSION OF REFERENCES

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicants note that the Submission of References dated September 20, 2004 contained a typographical error. Specifically, the date of reference JP 2002009569 should be 01/2002 not 01/2001. Below is a corrected listing of the previously submitted references.

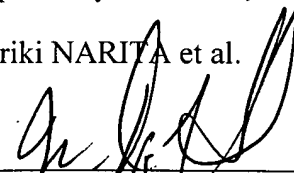
USP 6,198,616, 03/2001, Dahimene et al.  
JP 01077111, 03/1989 (Abstract)  
JP 2002009569, 01/2002 (Abstract)  
JP 2002203995, 07/2002 (Abstract)

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEE FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975.

Respectfully submitted,

Shoriki NARITA et al.

By

  
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October 20, 2004

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